

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: **Tamotsu OWADA et al.**

Serial Number: Not Yet Assigned

Filed: October 29, 2003

Customer No.: 38834

For: **SILICON OXYCARBIDE, GROWTH METHOD OF SILICON OXYCARBIDE LAYER, SEMICONDUCTOR DEVICE AND MANUFACTURE METHOD FOR SEMICONDUCTOR DEVICE**

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

October 29, 2003

Sir:

In compliance with 37 CFR 1.56, Applicants call to the attention of the Patent and Trademark Office the references listed on the attached PTO-1449.

A copy of the reference is enclosed herewith, except for the U.S. reference.

In the event there are any fees due in connection with the filing of this paper, please charge

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Respectfully submitted,
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**INFORMATION
DISCLOSURE
STATEMENT
PTO-1449**

Atty. Docket No. 032060

Serial No. New Appln.

Applicant(s): Tamotsu OWADA et al.

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Group Art Unit:

U.S. PATENT DOCUMENTS

Examiner Initial	Document No.	Name	Date	Class	Subclass	Filing Date (If appropriate)
_____	AA	2003/0134505 Dalton et al.	07/17/03			
_____	AB					
_____	AC					
_____	AD					

FOREIGN PATENT DOCUMENTS

	Document No.	Date	Country	Translation (Yes or No)
_____	AE	2003-218109	07/31/03 Japan	No. Discussed in the specification.
_____	AF			
_____	AG			
_____	AH			
_____	AI			

OTHER DOCUMENTS

_____	AJ	
_____	AK	

Examiner

Date Considered